



Corres. and Mail  
**BOX AF**

*FW*  
*AF*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**

Norio KIMURA et al. : Docket No. 2001-0660A

Serial No. 09/864,208 : Group Art Unit 1763

Filed May 25, 2001 : Examiner Jeffrie R. Lund

SUBSTRATE POLISHING APPARATUS : **MAIL STOP: AF**  
AND SUBSTRATE POLISHING METHOD

**RESPONSE UNDER 37. CFR 1.116**

**EXPEDITED PROCEDURE**

**EXAMINING GROUP** 1763

**AMENDMENT AFTER FINAL REJECTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

Sir:

In response to the Office Action of May 16, 2005, kindly amend the above-referenced  
U.S. patent application as follows: